

Description

Background of the Invention

The present invention generally relates to piezoelectric laminates and their manufacture, and in particular concerns a method of manufacturing a piezoelectric laminate in which the piezoelectric layer may be poled after it has been bonded to a rigid substrate layer.

Piezoelectric laminates typically comprise a layer of piezoelectric material bonded to a rigid insulating substrate material by an insulating elastically stiff or rigid bond layer. Such laminates are widely used in the manufacture of piezoelectric transducer arrays. Typical applications include the formation of phased array ultrasonic transducers and as components of ink jet printheads.

The bond layer, which normally has a rigidity comparable with that of the piezoelectric material or of the ceramic or glass substrate, generally has to be formed at an elevated temperature above or possibly just below the Curie temperature of the piezoelectric material. If exposed to these temperatures, the piezoelectric material may lose or have its remnant polarization substantially reduced. As a consequence, the piezoelectric material cannot be effectively pre-poled before forming the bond layer. Poling therefore preferably takes place subsequent to the formation of the bond layer.

Conventionally, the assembled piezoelectric laminate is poled by establishing a poling field between a pair of metal electrodes applied to the opposite faces of the laminate. This poling configuration has heretofore required the establishment of an impractically large poling field to effect adequate poling in a reasonable time period. That is, because of the high dielectric constant of the piezoelectric material relative to that of the substrate, a relatively small portion of the poling field is applied across the piezoelectric layer. Consequently, the strength of the poling field must be increased by a relatively large factor to effect poling, but frequently the extent of increase required is simply impractical.

Objects of the Invention

It is therefore a basic object of the present invention to provide an improved piezoelectric laminate and its method of manufacture.

It is a further object of the invention to provide an improved method for forming a piezoelectric laminate in which the piezoelectric material may be poled after the laminate has been formed.

It is yet another object of the invention to provide an improved method for forming a piezoelectric laminate in which the piezoelectric material

may be poled after the laminate has been formed, the poling operation taking place using practical poling fields.

EP-A-0 277 703 published on 10th August 1988 discloses a laminate comprising a first layer of piezoelectric material rigidly bonded to a second insulating layer. In that document the laminate is formed with piezoelectric material which is poled before being bonded to the second layer. The present invention is however concerned with poling the piezoelectric layer after bonding thereof to the second layer.

The present invention consists in the method of forming a poled laminate including a first layer of piezoelectric material and a second layer of material which is electrically insulating under normal operating conditions of the laminate and which is rigidly bonded to said piezoelectric layer, characterised by rendering conductive said normally insulating layer and applying a poling voltage across said laminate for a period greater than the time constant of the laminate prevailing during poling.

In one embodiment, the invention further consists in applying said poling voltage to said laminate at a temperature at which the conductivity of said second layer is substantially enhanced.

Suitably, the invention further consists in providing said second layer as a bond layer between said piezoelectric layer and a third layer of insulating material.

The invention also consists in a piezoelectric laminate comprising a first layer of piezoelectric material and a second layer which is rigidly bonded to said first layer and is of material which is electrically insulating under normal operating conditions, characterised in that said second layer has a conductivity at the poling temperature which is substantially greater than the conductivity of said first layer whereby a field not substantially greater than that required to pole said first layer alone may be used to effect poling of the laminate.

Suitably, said second layer forms a bond layer between and is rigidly bonded to said first layer and a third layer of insulating material, said bond layer being rendered conductive in response to a selected stimulus so as to act as an electrode for facilitating the application of a poling voltage across said first layer.

Brief Description of the Drawings

The invention will now be described with reference to the accompanying drawings, in which:

FIGURES 1(a) and 1(b) illustrate two forms of piezoelectric laminates which may be fabricated according to one embodiment of the present invention;

FIGURE 2(a) illustrates the laminate of Figure 1-(a) with the application of poling electrodes; FIGURE 2(b) illustrates a piezoelectric laminate constructed according to a second embodiment of the present invention; and FIGURE 3 graphically illustrates the variation with temperature of the conductivity of a piezoelectric ceramic and of a ceramic or glass substrate suitable for poling a laminate according to the present invention.

Description of the Preferred Embodiments

FIGURE 1(a) illustrates one form of a laminated ceramic component 10, comprising on one face a sheet or layer of piezoelectric material 12 and on the other face a sheet or layer of rigid insulating material 14. The two layers 12 and 14 of component 10 are bonded together by a suitable bond layer 16. The illustrated component may be subjected to further manufacturing processes for eventual use as an ultrasonic phased array transducer or as an ink jet array printhead component. The present invention is concerned with the manufacture and poling of the laminate component 10.

In a preferred form of the invention, the piezoelectric material 12 comprises a sheet of lead zirconium titanate (PZT) piezoelectric ceramic, but it will be understood that other piezoelectric ceramic or crystalline materials which become piezoelectric as the result of poling by application of an electric poling field can be employed within the scope of the invention. Also, the rigid insulating sheet 14 preferably comprises a sheet of glass or ceramic (or glass-ceramic) but other insulating materials may similarly be used.

Preferably, the values of the elastic modulus and density of the insulating sheet 14 are chosen so that its acoustic impedance has a specified value relative to that of the piezoelectric material 12 to obtain a defined acoustic performance. Alternatively, the elastic modulus of sheet 14 may be chosen to be equal to or greater than that of the piezoelectric material 12 to stiffen the substrate against low frequency deformation of the parts of a piezoelectric array transducer. The thermal expansion coefficient of the insulating sheet 14 should at the same time be chosen to closely match that of the piezoelectric material 12. This choice provides a laminate component 10 which is thermally matched for use over a practical operating range (typically -20 to +100 degrees centigrade) so that during manufacture and operation the bond layer is not subjected to significant thermal stress which could deleteriously affect the integrity of the laminate. Laminate component 10 will also have little or no tendency to bend under thermal variations. The dielectric constant of the insulating sheet 14 is also

preferably chosen to be substantially less than that of the piezoelectric sheet 12 (e.g. 10-100 times less) so that operating electric fields in the piezoelectric layer 12 are suitably confined thereto to prevent deleterious electrical crosstalk between multiple components 10 in a transducer array.

The bond layer 16 between the piezoelectric sheet 12 and the insulating sheet 14 may take a number of forms depending on the manufacturing process. In one case the bond layer 16 may comprise a ceramic-ceramic bond which results from the co-firing of the two ceramic sheets in a furnace during manufacture. The bond layer 16 may also comprise a PZT-glass bond in the case that the piezoelectric layer 12 is thermally bonded to a glass or glass-ceramic sheet or may comprise a thin glass sheet bond for fusing the PZT and ceramic sheets 12 and 14 together at a temperature suitably above or immediately below the Curie temperature of the PZT ceramic 12. In each case the bond layer 16 should satisfy the same design requirements as the insulating sheet 14 in regard to its elastic modulus and density in the operating range, to provide appropriate acoustic impedance or stiffness, and should also possess bond strength values, having regard to thermal, manufacturing and operating stresses adequate for component integrity during its service life.

The laminated ceramic component 10 may take other forms than that illustrated in Figure 1(a). For example, a laminate component 10 is illustrated in Figure 1(b) comprising three layers. In this embodiment, a piezoelectric sheet 12 is bonded to each of the opposing faces of an insulating sheet 14 by respective bond layers 16.

As previously described, when the bond layer 16 is formed above the Curie temperature of the piezoelectric sheet 12, or is formed at a temperature immediately below its Curie temperature, the remnant polarization of the piezoelectric sheet may be lost or reduced substantially. A technique for poling or for maintaining the state of polarization of the piezoelectric material 12 after forming the bond must therefore be provided.

Referring initially to Figure 3, curve A illustrates the typical electrical resistivity of PZT as a function of temperature. It will be observed that typically the resistivity of this material is about $\rho = 10^{13}$ ohm-cm at 100 degrees centigrade. A charged piezoelectric transducer has a time constant $\epsilon\epsilon_0\rho$ (where ϵ is the relative dielectric constant of the material and ϵ_0 is the permittivity of free space). At 100 degrees centigrade and for $\epsilon = 2300$, the time constant over which PZT holds a charge is about 0.72 hours. Curve A of Figure 3 is also typical of many insulating glasses and ceramics in addition to PZT. The resistivity of PZT can be increased by about two orders of magnitude or decreased to about the

same degree by appropriate doping. Glasses and ceramics of different resistivity can also be formulated, these materials having resistivity curves generally parallel to that of PZT.

Conventionally, piezoelectric materials are pol-
ed by applying metal electrodes to each face of a
piezoelectric sheet and applying a poling field
there between. A state of saturated poling is
achieved in a time short compared with the time
constant $\epsilon\epsilon_0\rho$ of the PZT sheet. This technique as
applied to the laminate component 10 of Figure 1-
(a) is illustrated in Figure 2(a) wherein a pair of
electrodes 18 and 19 are applied to the opposite
faces of the component. Because the dielectric
constant of the piezoelectric sheet 12 is relatively
large compared to that of the substrate sheet 14,
only a fraction of the applied field is effectively
available for poling the piezoelectric layer 12. Con-
sequently, the poling field has to be elevated by a
very large factor (e.g. 100) to achieve effective
poling, which is frequently not practical. The
present invention provides solutions to these prob-
lems as described in detail below.

In one form of the invention, the insulating
sheet 14 is formed from a ceramic, glass or glass-
ceramic characterized by curve B of Figure 3,
which has a resistivity lower, typically by two or-
ders of magnitude, than that of the PZT forming
piezoelectric layer 12. This resistivity characteris-
tic may be achieved by appropriately doping insulat-
ing sheet 14. The laminate component 10 is then
held at a suitable poling temperature and a poling
field is applied to electrodes 18 and 19 as illus-
trated in Figure 2(a). If, for example, the tempera-
ture is 100 degrees centigrade, the time constant
for the field to rise to equilibrium by charge leak-
age through insulating sheet 14 is about $1/100 \times 0.72\text{hrs} = 20$ seconds, assuming that the time con-
stant for the laminate is governed by the dominat-
ing dielectric constant of the PZT layer 12 and by
the dominating resistivity of the doped insulating
layer 14. The field across the PZT layer 12 is now
controlled after these rise times by the resistance
(or conductance) ratio rather than the dielectric
constant ratio of the PZT and substrate sheets 12
and 14, and a field for poling applied between
electrodes 18 and 19 not substantially greater than
would be required between electrodes on an iso-
lated PZT sheet is adequate for poling.

In other words, by increasing the poling tem-
perature and conductivity of the substrate layer 14,
it is arranged that after a relatively short time
interval during which the ratio of dielectric con-
stants is of primary importance, the division of the
electric field applied across the laminate is gov-
erned not by considerations of dielectric constants
(which are unfavourable in this regard), but by
considerations of resistivity which can be arranged

to be favourable by enhancing the conductivity of
the substrate layer as described. Under these con-
ditions, maintenance of the poling field for a time
period greater than the time constant of the lami-
nate results in a substantial part of the poling
voltage being dropped across the piezoelectric lay-
er, thereby allowing the use of a practical poling
field. It has been found that increasing the con-
ductivity of the substrate 14 by one or preferably
two orders of magnitude relative to the piezoelec-
tric layer 12 has no detrimental effect on the nor-
mal operation of laminate 10 or a device con-
structed therefrom, provided that the reduced time
constant remains large compared with the period of
the periodic actuation of the device, as will usually
be the case. It will also be understood that in this
embodiment bond layer 16 may be omitted, it only
being essential that a poling potential is created at
the boundary between the piezoelectric and sub-
strate layers 12 and 14, which boundary may com-
prise a region where the latter two layers are
mutually diffused.

Suitable dopants to lower the resistivity of a
glass, ceramic or glass-ceramic insulating substrate
14 are well known in the art and include Sc, Mg
and La ions which introduce oxygen vacancies in
the glass lattice. Materials such as Bi and Po can
also be used to enrich the metal content of sub-
strate 14. Increasing the temperature at which pol-
ing occurs will further reduce the time constant.
Thus the time constant for a PZT layer alone at
200 degrees centigrade is typically 1 second with
the value for the laminate falling approximately to
1/100 second.

An alternative embodiment of the invention is
illustrated in Figure 2(b). Bond layer 16 between
piezoelectric and substrate layers 12 and 14 is
characterized by an electrical switching property,
by which it may be selectively switched between
electrically conductive and resistive states. For ex-
ample, bond layer 16 may comprise a fusible glass
layer which is electrically conductive above a given
temperature and resistive below the given tempera-
ture. Chalcogenide glasses having such character-
istics are well known. Glasses having suitable vari-
ation in ionic conduction over the temperature
range similar in property to glasses of curve B of
Figure 3 may also be suitably used to effect poling,
including vanadium oxide and lanthanum oxide
glasses or frits.

In this embodiment the control of resistivity
with temperature is confined to the bond layer 16
and the insulating base sheet 14 is preferably
chosen with higher resistivity comparable with PZT
as represented by curve A of Figure 3. Poling is
facilitated by applying one electrode 18 to the
external face of the piezoelectric layer 12 with the
second electrode being provided by the fusible

glass layer in its conductive state. Electrical access to the bond layer 16 may be provided by a conductive track 21 formed along the edge of substrate sheet 14 and disposed between the sheet and bond layer 16. The conductive track will normally be removed by dressing the edges of the laminate component after poling as shown by the dotted lines in Fig. 2(b). Heat may be applied to control the temperature and thereby the conductivity of bond layer 16 by any of a number of well known techniques.

In a further implementation of the embodiment of Figure 2(b), the substrate sheet 14 is optically translucent and the fusible glass bond layer 16 is replaced by a fusible glass photo-conductor which may be switched to a conductive state by means of an optical beam instead of thermal switching. Optically glass photo-conductors are also well known. Examples include amorphous silicon.

In both of the latter two embodiments, after a time period corresponding to the time constant of the piezoelectric layer 12, substantially the entire poling field is applied across the piezoelectric layer. The poling field is then maintained for a sufficient period of time to properly pole the layer.

Claims

1. Method of forming a poled laminate including a first layer (12) of piezoelectric material and a second layer (16) of material which is electrically insulating under normal operating conditions of the laminate and which is rigidly bonded to said piezoelectric layer, characterised by rendering conductive said normally insulating layer and applying a poling voltage across said laminate for a period greater than the time constant of the laminate prevailing during poling.
2. The method of Claim 1, characterised by applying said poling voltage to said laminate at a temperature at which the conductivity of said second layer (16) is substantially enhanced.
3. The method of Claim 2, characterised by applying said poling voltage to said laminate at a temperature at which the conductivity of said second layer (16) is greater than that of said first layer (12) by at least an order of magnitude.
4. The method of Claim 3, including the step of doping said second layer to increase its conductivity.
5. The method of Claim 1, characterised by providing said second layer as a bond layer (16) between said piezoelectric layer (12) and a third layer (14) of insulating material.
6. The method of Claim 5, characterised by heating said laminate to a temperature at which said second layer (16) is rendered conductive and applying said poling voltage across said first and second layers between said second layer and an electrode on the face of said first layer remote from said second layer.
7. The method of Claim 5, characterised by optically rendering said second layer (16) conductive and applying said poling voltage across said first and second layers between said second layer and an electrode on a face of said first layer remote from said second layer.
8. A piezoelectric laminate comprising a first layer (12) of piezoelectric material and a second layer (16) which is rigidly bonded to said first layer and is of material which is electrically insulating under normal operating conditions, characterised in that said second layer has a conductivity at the poling temperature which is substantially greater than the conductivity of said first layer whereby a field not substantially greater than that required to pole said first layer alone may be used to effect poling of the laminate.
9. A piezoelectric laminate as claimed in Claim 8, characterised in that said second layer forms a bond layer (16) between and is rigidly bonded to said first layer (12) and a third layer (14) of insulating material, said bond layer being rendered conductive in response to a selected stimulus so as to act as an electrode for facilitating the application of a poling voltage across said first layer.
10. A piezoelectric laminate as claimed in Claim 9, characterised in that said second layer (16) comprises a material responsive to its temperature exceeding a threshold temperature for switching to its conductive state and which is non-conductive below said threshold temperature.
11. A piezoelectric laminate as claimed in Claim 9, characterised in that said second layer (16) comprises a material responsive to exposure to light for switching to its conductive state and which is otherwise in its non-conductive state.



glass layer in its conductive state. Electrical access to the bond layer 16 may be provided by a conductive track 21 formed along the edge of substrate sheet 14 and disposed between the sheet and bond layer 16. The conductive track will normally be removed by dressing the edges of the laminate component after poling as shown by the dotted lines in Fig. 2(b). Heat may be applied to control the temperature and thereby the conductivity of bond layer 16 by any of a number of well known techniques.

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In both of the latter two embodiments, after a time period corresponding to the time constant of the piezoelectric layer 12, substantially the entire poling field is applied across the piezoelectric layer. The poling field is then maintained for a sufficient period of time to properly pole the layer.

Claims

1. Method of forming a poled laminate including a first layer (12) of piezoelectric material and a second layer (16) of material which is electrically insulating under normal operating conditions of the laminate and which is rigidly bonded to said piezoelectric layer, characterised by rendering conductive said normally insulating layer and applying a poling voltage across said laminate for a period greater than the time constant of the laminate prevailing during poling.
2. The method of Claim 1, characterised by applying said poling voltage to said laminate at a temperature at which the conductivity of said second layer (16) is substantially enhanced.
3. The method of Claim 2, characterised by applying said poling voltage to said laminate at a temperature at which the conductivity of said second layer (16) is greater than that of said first layer (12) by at least an order of magnitude.
4. The method of Claim 3, including the step of doping said second layer to increase its conductivity.
5. The method of Claim 1, characterised by providing said second layer as a bond layer (16)

between said piezoelectric layer (12) and a third layer (14) of insulating material.

6. The method of Claim 5, characterised by heating said laminate to a temperature at which said second layer (16) is rendered conductive and applying said poling voltage across said first and second layers between said second layer and an electrode on the face of said first layer remote from said second layer.
7. The method of Claim 5, characterised by optically rendering said second layer (16) conductive and applying said poling voltage across said first and second layers between said second layer and an electrode on a face of said first layer remote from said second layer.
8. A piezoelectric laminate comprising a first layer (12) of piezoelectric material and a second layer (16) which is rigidly bonded to said first layer and is of material which is electrically insulating under normal operating conditions, characterised in that said second layer has a conductivity at the poling temperature which is substantially greater than the conductivity of said first layer whereby a field not substantially greater than that required to pole said first layer alone may be used to effect poling of the laminate.
9. A piezoelectric laminate as claimed in Claim 8, characterised in that said second layer forms a bond layer (16) between and is rigidly bonded to said first layer (12) and a third layer (14) of insulating material, said bond layer being rendered conductive in response to a selected stimulus so as to act as an electrode for facilitating the application of a poling voltage across said first layer.
10. A piezoelectric laminate as claimed in Claim 9, characterised in that said second layer (16) comprises a material responsive to its temperature exceeding a threshold temperature for switching to its conductive state and which is non-conductive below said threshold temperature.
11. A piezoelectric laminate as claimed in Claim 9, characterised in that said second layer (16) comprises a material responsive to exposure to light for switching to its conductive state and which is otherwise in its non-conductive state.



Patentansprüche

1. Verfahren zur Herstellung eines polarisierten Laminats, mit einer ersten Schicht bzw. Lage (12) aus piezoelektrischem Material und einer zweiten Lage bzw. Schicht (16) aus einem Material, welches unter normalen Betriebsbedingungen des Laminats elektrisch isolierend ist und welches starr mit der piezoelektrischen Lage bzw. Schicht verbunden ist, dadurch **gekennzeichnet**, daß die normalerweise isolierende Schicht bzw. Lage leitend gemacht wird und eine polarisierende Spannung über das Laminat für eine Periode angelegt wird, die größer ist als die Zeitkonstante des Laminats, die während des Polarisierens gegeben ist.
2. Verfahren nach Anspruch 1, dadurch **gekennzeichnet**, daß die Polarisierungsspannung bei einer Temperatur an das Laminat angelegt wird, bei welcher die Leitfähigkeit der zweiten Lage bzw. Schicht (16) beträchtlich verstärkt ist.
3. Verfahren nach Anspruch 2, **gekennzeichnet** durch Anlegen der Polarisierungsspannung an das Laminat bei einer Temperatur, bei welcher die Leitfähigkeit der zweiten Lage bzw. Schicht (16) zumindest um eine Größenordnung größer ist als die der ersten Lage bzw. Schicht (12).
4. Verfahren nach Anspruch 3, das den Schritt enthält, die zweite Lage bzw. Schicht zu dotieren, um seine Leitfähigkeit zu erhöhen.
5. Verfahren nach Anspruch 1, dadurch **gekennzeichnet**, daß die zweite Lage bzw. Schicht als eine Bindschicht bzw. -lage (16) zwischen der piezoelektrischen Schicht bzw. Lage (12) und einer dritten Lage bzw. Schicht (14) aus isolierendem Material vorgesehen wird.
6. Verfahren nach Anspruch 5, **gekennzeichnet** durch Erhitzen des Laminats auf eine Temperatur, bei welcher die zweite Lage bzw. Schicht (16) leitfähig gemacht wird, und Anlegen der Polarisierungsspannung über die erste und zweite Lage bzw. Schicht zwischen der zweiten Lage bzw. Schicht und einer Elektrode an der Fläche der ersten Lage bzw. Schicht fern von der zweiten Lage bzw. Schicht.
7. Verfahren nach Anspruch 5, dadurch **gekennzeichnet**, daß die zweite Schicht bzw. Lage (16) optisch leitend gemacht wird, und daß die Polarisierungsspannung über die erste und die zweite Schicht bzw. Lage zwischen der zweiten Schicht bzw. Lage und einer Elektrode auf

einer Fläche der ersten Schicht bzw. Lage, die entfernt von der zweiten Schicht bzw. Lage ist, angelegt wird.

8. Piezoelektrisches Laminat mit einer ersten Schicht bzw. Lage (12) aus piezoelektrischem Material und einer zweiten Schicht bzw. Lage (16), welche starr mit der ersten Schicht bzw. Lage verbunden ist, und aus einem Material ist, welches unter normalen Betriebsbedingungen elektrisch isolierend ist, dadurch **gekennzeichnet**, daß die zweite Schicht bzw. Lage eine Leitfähigkeit bei der Polarisierungstemperatur aufweist, welche beachtlich bzw. wesentlich größer ist als die Leitfähigkeit der ersten Schicht bzw. Lage, wobei ein Feld, das nicht beträchtlich größer ist als das zum Polarisieren der ersten Schicht bzw. Lage allein erforderliche, zum Verursachen der Polarisierung des Laminats verwendet werden kann.
9. Piezoelektrisches Laminat nach Anspruch 8, dadurch **gekennzeichnet**, daß die zweite Schicht bzw. Lage eine Bindschicht bzw. -lage (16) zwischen der ersten Schicht bzw. Lage (12) und einer dritten Schicht bzw. Lage (14) aus isolierendem Material bildet und starr mit diesen verbunden ist, wobei die Bindschicht bzw. -lage in Abhängigkeit zu einer ausgewählten Anregung bzw. Stimulation leitfähig gemacht wird, um so als eine Elektrode zu wirken, um das Anlegen einer Polarisierungsspannung über die erste Lage bzw. Schicht zu vereinfachen.
10. Piezoelektrisches Laminat nach Anspruch 9, dadurch **gekennzeichnet**, daß die zweite Schicht bzw. Lage (16) ein Material aufweist, das auf seine Temperatur, die eine Schwelltemperatur zum Schalten in seinen leitenden Zustand übersteigt, anspricht, und welches unterhalb der Schwelltemperatur nicht leitfähig ist.
11. Piezoelektrisches Laminat nach Anspruch 9, dadurch **gekennzeichnet**, daß die zweite Lage bzw. Schicht (16) ein Material aufweist, das auf Belichtung anspricht, um in seinen leitenden Zustand zu schalten und welches ansonsten in seinem nicht-leitenden Zustand ist.

Revendications

1. Méthode de fabrication d'un laminé polarisé comprenant une première couche (12) de matière piézoélectrique et une deuxième couche (16) de matière qui est électriquement isolante



dans les conditions normales de fonctionnement du laminé et qui est rigidement liée à ladite couche piézoélectrique, caractérisée en ce qu'on rend conductrice ladite couche normalement isolante et on applique une tension de polarisation à travers ledit laminé pendant une durée plus grande que la constante de temps du laminé qui existe pendant la polarisation.

2. Méthode suivant la revendication 1, caractérisée en ce qu'on applique ladite tension de polarisation audit laminé à une température à laquelle la conductivité de ladite deuxième couche (16) est sensiblement augmentée.

3. Méthode suivant la revendication 2, caractérisée en ce qu'on applique ladite tension de polarisation audit laminé à une température à laquelle la conductivité de ladite deuxième couche (16) est plus grande que celle de ladite première couche (12), d'au moins un ordre de grandeur.

4. Méthode suivant la revendication 3, comprenant l'étape de dopage de ladite deuxième couche pour augmenter sa conductivité.

5. Méthode suivant la revendication 1, caractérisée en ce que ladite deuxième couche est réalisée comme une couche de liaison (16) entre ladite couche piézoélectrique (12) et une troisième couche (14) de matière isolante.

6. Méthode suivant la revendication 5, caractérisée en ce qu'on chauffe ledit laminé à une température à laquelle ladite deuxième couche (16) est rendue conductrice et on applique ladite tension de polarisation à travers lesdites première et deuxième couches, entre ladite deuxième couche et une électrode appliquée sur la face de ladite première couche éloignée de ladite deuxième couche.

7. Méthode suivant la revendication 5, caractérisée en ce que ladite deuxième couche (16) est rendue conductrice de façon optique, et on applique ladite tension de polarisation à travers lesdites première et deuxième couches, entre ladite deuxième couche et une électrode appliquée sur une face de ladite première couche qui est à l'opposé de ladite deuxième couche.

8. Laminé piézoélectrique comprenant une première couche (12) de matière piézoélectrique et une deuxième couche (16) qui est rigidement liée à ladite première couche et qui est en une matière électriquement isolante dans

les conditions normales de fonctionnement, caractérisé en ce que ladite deuxième couche a une conductivité, à la température de polarisation, qui est sensiblement supérieure à la conductivité de ladite première couche, de sorte qu'un champ qui n'est pas sensiblement plus grand que celui qui est requis pour polariser ladite première couche seule peut être utilisé pour effectuer la polarisation du laminé.

9. Laminé piézoélectrique suivant la revendication 8, caractérisé en ce que ladite deuxième couche forme une couche de liaison (16) entre ladite première couche (12) et une troisième couche (14) de matière isolante et elle est rigidement liée à ces dernières, ladite couche de liaison étant rendue conductrice en réponse à une stimulation choisie, de façon à agir comme une électrode pour faciliter l'application d'une tension de polarisation à travers ladite première couche.

10. Laminé piézoélectrique suivant la revendication 9, caractérisé en ce que ladite deuxième couche (16) est en une matière qui répond au fait que sa température dépasse un seuil de température pour passer à son état conducteur, et qui est non conductrice au-dessous dudit seuil de température.

11. Laminé piézoélectrique suivant la revendication 9, caractérisé en ce que ladite deuxième couche (16) est en une matière qui répond à l'exposition à la lumière pour passer à son état conducteur, et qui est sinon dans son état non conducteur.